

Cleanroom space

Characterization space

T table

S storage shelves

P pump

CS chemical storage

C chiller or compressor

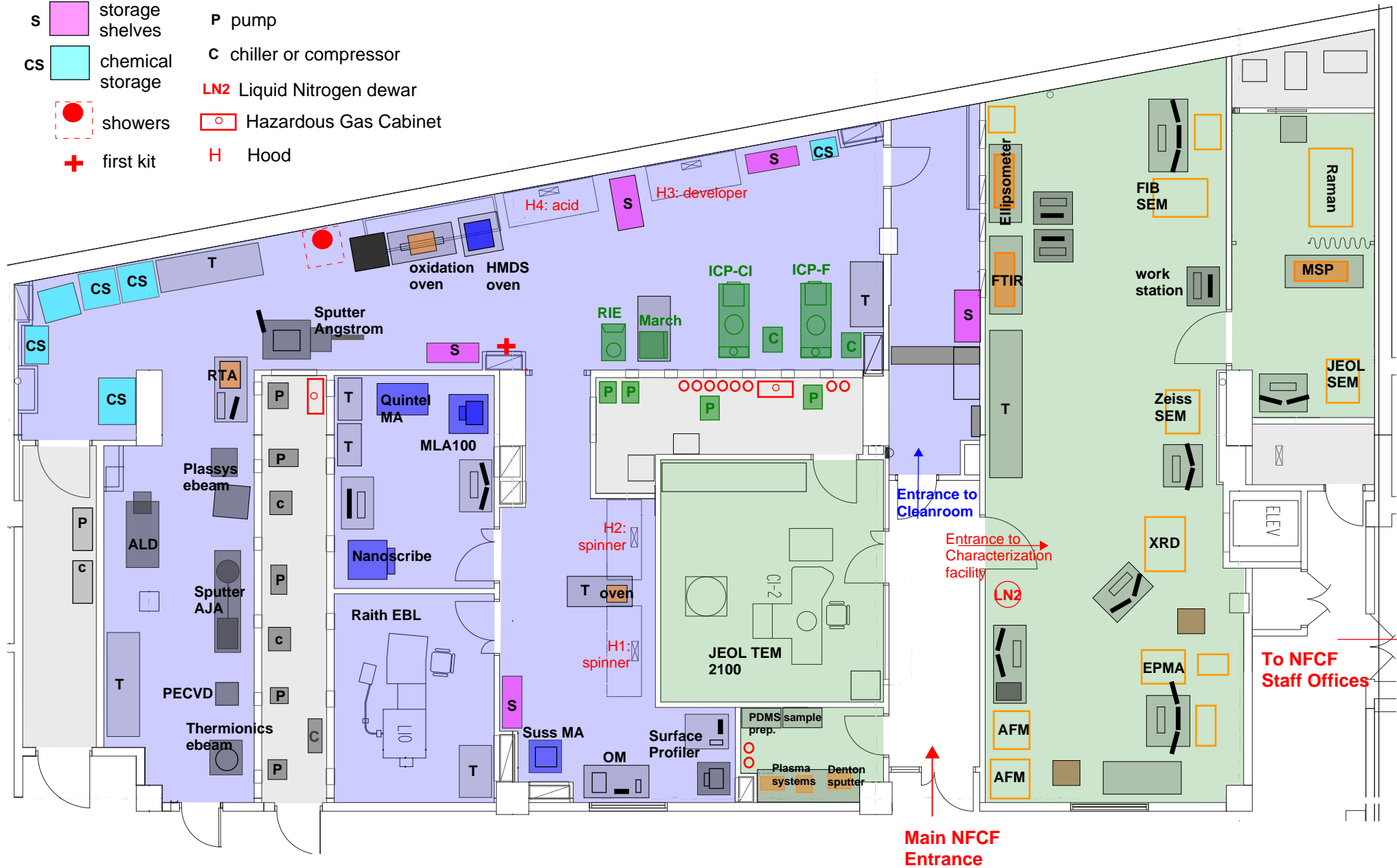
LN2 Liquid Nitrogen dewar

showers

Hazardous Gas Cabinet

+ first kit

H Hood



Main NCFE Entrance

To NCFE Staff Offices

Entrance to Cleanroom

Entrance to Characterization facility

LN2

H2: spinner

H1: spinner

H4: acid

H3: developer

Sputter Angstrom

Plassys ebeam

Sputter AJA

Thermionics ebeam

Raith EBL

Suss MA

Surface Profiler

PDMS sample prep.

Plasma systems

Denten sputter

JEOL TEM 2100

T oven

Nanoscribe

MLA100

Quintel MA

RIE

March

ICP-CI

ICP-F

oxidation oven

HMDS oven

work station

Zeiss SEM

XRD

EPMA

AFM

AFM

JEOL SEM

Raman

MSP

FIB SEM

FTIR

Elipsometer

ELEV